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Docket: 740756-2092

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Koichiro TANAKA

Serial No. 09/481,396

Filed: January 12, 2000

For: LASER IRRADIATION APPARATUS

) Art Unit: 2877

) Examiner: A. Rodriguez

) Date: October 31, 200

PRELIMINARY AMENDMENT

Honorable Commissioner for Patents and Trademarks

Washington, D.C. 20231

Sir:

Please preliminarily amend the subject application as follows:

IN THE CLAIMS:

Please add new claims 18-38 as follows:

--18. An apparatus according to claim 2 further comprising a stage for holding a substrate having a semiconductor film thereon,

wherein said semiconductor film is crystallized by irradiating with the laser beam.

An apparatus according to claim wherein said slit comprises at least one of the group consisting of glass, quartz, ceramic, and metal.

An apparatus according to claim 2 wherein said optical system for overlapping divided laser beams is a convex lens.

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